

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 231752US41YA		SERIAL NO. 10/673,467	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Eric J STRANG, et al.			
				FILING DATE September 30, 2003		GROUP 2128	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA	US 2002/0032495 A1	3/14/2002	Ozaki			
	AB	US 5,719,796	2/17/1998	CHEN			
	AC						
	AD						
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	AH						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
	AI	CN 1335558A	2/13/2002	China (with Partial English Translation))	X		
	AJ	EP 0 718 595 A2	6/26/1996	EUROPE	X	X	
	AK	JP 11-176906	7/2/1999	JAPAN (with English Abstract)		X	
	AL	KR 1999-071784	4/2/1999	Korea (with corresponding to US. Patent Application No. 5,719,796 attached as a courtesy herewith)	X		
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AL	Agam SHAH, "TILERA TARGETS INTEL, AMD WITH 100-CORE PROCESSOR", PCWorld Solved, IDG News October 26, 2009, pages 1-3					
	AM	Robert W. ATHERTON, et al., "DETAILED SIMULATION FOR SEMICONDUCTOR MANUFACTURING", Proceedings of the 1990 Winter Simulation Conference, ppgs 659-663					
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	AO	Paul P. CASTRUCCI, et al. "EMERGING PARADIGMS IN SEMICONDUCTOR MANUFACTURING", 1990 International Semiconductor Manufacturing Science Symposium, pages 21-23					
	AP	Yea-Huey Su, et al, "A CONCEPTUAL FRAMEWORK FOR MANUFACTURING SERVICE PROVISIONING BY VIRTUAL FABS", 1998 Semiconductor Manufacturing Technology Workshop, pages 75-85					
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	AR	Office Action issued March 30, 2011 in Japanese Patent Application No. 10-2006-7006632, (with English-language Translation) pages 1-17					
	AS	Su-shing CHEN, "AEMPES: An expert system for in-situ diagnostics and process monitoring", Semiconductor Manufacturing Science Symposium, 1990, IEEE/SEMI International, 21-23 May 1990, pages 119-122					
	AT					<input type="checkbox"/> Additional References sheet(s) attached	
Examiner					Date Considered		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							